



제 30회 한국반도체학술대회

The 30th Korean Conference on Semiconductors

2023년 2월 13일(월)~ 15일(수) | 강원도 하이원리조트(그랜드호텔 컨벤션타워)

2023년 2월 14일(화), 10:55-12:40

Room B (에메랄드 II+III, 5층)

D. Thin Film Process Technology 분과

[TB2-D] Thin Films Analysis

좌장: 이응규 교수(숭실대학교), 김성근 책임연구원(한국과학기술연구원)

<p>TB2-D-1 10:55-11:25 [초청]</p>	<p>Mono EELS Applications for Oxide and OLED and Atomic Level Imaging Denoising Method with Machine Learning Jae Hyuck Jang^{1,2} <i>¹Center for Electron Microscopy Research, KBSI, ²Graduate School of Analytical Science and Technology (GRAST)</i></p>
<p>TB2-D-2 11:25-11:55 [초청]</p>	<p>Visualizing Ultrathin Films Using Advanced Hard X-ray Scattering Techniques Seo Hyoung Chang <i>Department of Physics, Chung-Ang University</i></p>
<p>TB2-D-3 11:55-12:25 [초청]</p>	<p>Probing Buried Interface with Hard XPS under Near-Total-Reflection Regime Deok-Yong Cho^{1,2} <i>¹Institute of Photonics, Electronics and Information Technology, Jeonbuk National University, ²Department of Physics, Jeonbuk National University</i></p>
<p>TB2-D-4 12:25-12:40</p>	<p>Measurement Technology of ALD Process based on Cocktail Precursor Replacing Super-cycle ALD Process Hayeong Kim^{1,2}, Jiwon Park^{1,3}, Jaeuk Lim^{1,3}, SeonJeong Maeng¹, and Ju-Young Yun^{1,4} <i>¹Vacuum Materials Measurement Team, KRISS, ²Nanomaterials Science and Engineering, University of Science and Technology (UST), ³Department of Advanced Materials Engineering, Daejeon University, ⁴Nanoscience and Technology, University of Science and Technology (UST)</i></p>